Customer No.: 31561 Application No.: 10/605,214 Docket No.: 9789-US-PA

- 1. (currently amended) A method of fabricating an organic light emitting diode device, comprising:
 - (a) providing a substrate having an organic light emitting diode unit thereon;
- (b) forming a passivation layer on the substrate to cover the organic light emitting diode unit; and
- (c) providing an ion beam to perform surface treatment on the passivation layer, wherein the ion beam is provided by ion implantation.
- 2. (original) The method according to Claim 1, wherein the passivation layer is formed of either silicon nitride or silicon oxide.

Claims 3-4 (cancelled)

- 5. (original) The method according to Claim 1, further comprising the step after step (c):
- (d) forming a plastic layer on the passivation layer.
- 6. (original) The method according to Claim 5, further comprising repeating the steps (b) to (d) at least once.

Customer No.: 31561 Application No.: 10/605,214 Docket No.: 9789-US-PA

- 7. (original) The method according to Claim 5, wherein the plastic layer is made of ultra high molecular weight polyethylene or PMMA.
- 8. (currently amended) A method of forming a solid passivation layer to protect an electronic device formed on a substrate, comprising:
 - (a) forming a passivation layer to cover the electronic device; and
- (b) providing an ion beam to perform surface treatment on the passivation layer, wherein the ion beam is provided by ion implantation.
- 9. (original) The method according to Claim 8, wherein the passivation layer is made of silicon nitride or silicon oxide.

Claims 10-11 (cancelled)

12. (original) The method according to Claim 8, further comprising the following step after the step (b):

Customer No.: 31561 Application No.: 10/605,214 Docket No.: 9789-US-PA

- (c) forming a plastic layer on the passivation layer.
- 13. (original) The method according to Claim 12, further comprising the step of repeating steps (a) to (c) at least once.
- 14. (original) The method according to Claim 12, wherein the plastic layer is made of ultra high molecular polyethylene or PMMA.